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INFORMATION
DISCLOSURE
CITATION
PTO-1449

Atty. Docket No. 970813 Serial No. 08/921,250

Applicant(s): INOUE, et al.

Filing Date: August 29, 1997 Group Art Unit: 1763

U.S. PATENT DOCUMENTS

Examiner Initial	Document No.	Name	Date	Class	Subclass	Filing Date (If appropriate)
gag	AA 5,892,269	Inoue et al.	4/1999			
	AB 6,235,648	Mizuhara et al.	5/2001			
	AC 6,288,438	Mizuhara et al.	9/2001			
gag	AD 5,459,086	Yang	10/1995			
	AE					

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Document No.	Date	Country	Translation (Yes or No)
AF 10-242278	9/11/98	Japan	Abstract
AG 10-270447	10/09/98	Japan	Abstract
AH 10-189724	7/21/98	Japan	Abstract
AI 09-293783	11/11/97	Japan	Abstract
AJ 10-242277	9/11/98	Japan	Abstract
AK 09-069562	3/11/97	Japan	Abstract
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OTHER DOCUMENTS

<i>[Handwritten signature]</i>	AM	Serial No. 09/320,271, Filed 5/27/99 (U. S. Publication No. 20010055873, Publication date 12/27/2001)
	AN	Serial No. 09/228,148, Filed 1/11/99, Docket No. 970813. <i>✓</i>
	AO	Serial No. 09/716,334, Filed 11/21/00, Docket No. 981187A. <i>✓</i>
	AP	Wolf, et al. "Silicon Processing for the VLSI Era: Volume 1 - Process Technology," Lattice Press, 1986 p.441. <i>✓</i>
	AQ	S. M. Sze, Physics of Semiconductor Device, "A Wiley Interscience publication.", p. 393, 1981. <i>✓</i>

Examiner

George Goudreau

Date Considered

5-031